

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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| In re Patent Application of:        | )                              |
| Koichiro TANAKA, et al.             | ) Group Art Unit: 3742         |
| Application No. 10/769,820          | ) Examiner: Samuel M. Heinrich |
| Filed: February 3, 2004             | ) Confirmation No. 9528        |
| For: LASER IRRADIATION STAGE, LASER | )                              |
| IRRADIATION OPTICAL SYSTEM, LASER   |                                |
| IRRADIATION APPARATUS, LASER        |                                |
| IRRADIATION METHOD, AND METHOD OF   |                                |
| MANUFACTURING A SEMICONDUCTOR       |                                |
| DEVICE                              |                                |

**SUBMISSION OF FORMAL DRAWINGS**

**MAILSTOP: Issue Fee**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Submitted herewith are four (4) sheets of formal drawings, consisting of Figures 4A, 4B, 6, 7A, 7B, 8A and 8B, for filing in the subject application.

Respectfully submitted,

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